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The small size of nanostructured layers is essential in applications of miniaturized optical systems. We obtained a multilayer of Ag/SiO<sub>2</sub>/Si and Au/SiO<sub>2</sub>/Si, exhibiting excellent qualities when silver was 7 nm thick and gold 5 nm thick, respectively; with plasmonic properties useful in obtaining structures with negative refractive index. Silicon dioxide has 200 nm thickness and high-performance dielectric properties, which improves the properties of metamaterial structures. The deposition conditions were optimized and led to layers with a good morphology of surface, consisting of nanoparticles with dimensions between 7 nm to 15 nm and a surface roughness between 0.5 nm to 1.3 nm. The analyzed XPS general scans showed the presence of Ag 3d3 and Ag 3d5 in the silver nanostructures and the presence of Au 4f5 and Au 4f7 in the gold nanostructures. The XRD diffractograms also indicated that both Ag and Au samples are crystalline. In the case of these noble samples the orientation was clearly after the main planes perpendicular to the substrate for the (111) planes. Good structural properties of the Ag/SiO<sub>2</sub>/Si and Au/SiO<sub>2</sub>/Si and Au/SiO<sub>2</sub>/Si multilayers were highlighted by the crystallographic quality, resulting from XRD analysis and a high spectral transmission in the visible and infrared range. Therefore, the obtained noble films have a controlled morphology suitable in future applications of structures with metamaterials.

## **Depositions conditions**

for Au, Ag thin films

Table 1 The optimized deposition conditions used to obtain Ag and Au thin films with nanostructured surfaces. INFLPF

Au, Ag and SiO<sub>2</sub> thin films were deposited on Si substrate;
All these thin films were prepared by *RF magnetron* sputtering;

SRF ()

- distance from substrate to target: 9 cm;
- 4 inch diameter target;
- 99.95% purity.

pressure during deposition: 5 × 10<sup>-3</sup> Torr

- mass flow controller: 20 sccm Ar;

- intensity of the electrical current: 0.1A;
- forward power/reflected power: 20W/0W;
- deposition rate: 1.1 Å/s.

substrate	target	Purity (%)	P (W)	d (sccm)	D (nm)	r (Å/s)	I (A)
				Ar			
SiO <sub>2</sub> /Si(100)	Au	99.99	20	15	5nm, 7 nm	1.1	0.1
SiO <sub>2</sub> /Si(100)	Ag	99.99	25	17	5nm, 7nm	1.0	0.1



3.00E





XPS analysis a)general spectra and b) HR of silver deposited films

110"

a)

Ag3p1

C1s

**Binding Energy (eV)** 

Ag3s

(10)

2.00E+05 1.00E+05 1.00E+05 4.100 102 101 100 99 98 79 69 95 544 542 540 538 536 534 532

b)

Binding Energy (eV)

**Table 2** The chemical composition of SiO<sub>2</sub> thin films by HR-XPS measurements.



## XPS analysis a)general spectra and b) HR of gold deposited

530 528 526

ding Energy (eV





In the case of thin Au and thin Ag layers deposited on the  $SiO_2$ /Si substrate, it has been observed the presence of chemical elements on the surface, such as: Au 4f5, Au4f7, Ag3d3 and Ag3d5. The XRD patterns indicated the Ag and Au films are crystalline and polycrystalline. Also, the Ag and Au thin films have a strong orientation after the main planes perpendicular to the substrate, e.g. (111) for Au films.

The present investigation of ultra thin films with small dimensions are useful for integration in the micro- and nanosatellites manufacturing.



C)

Ag thi

375

370

d. = 7 nm

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